

What is claimed is:

1. A wafer handling checker comprising:
 - a plurality of operation training wafers each formed of semiconductor or ceramics to which a conductive film is applied on the face thereof, or a material having conductive properties;
 - a cassette having a plurality of slots for housing the plurality of wafers, and a plurality of electrodes contacting the plurality of wafers when the plurality of wafers are inserted into the plurality of slots;
 - a vacuum pincette having a conductive suction part for operating each wafer;
 - voltage application means for applying a voltage between each electrode of the cassette and the suction part of the pincette; and
 - state detection means for detecting contact between the pincette and each wafer by detecting a potential of each electrode of the cassette or a current flowing to the electrode.
2. The wafer handling checker according to Claim 1, wherein the cassette has display means for specifying a wafer to be operated based on operation specification information.
3. The wafer handling checker according to Claim 2, further comprising decision means for deciding the presence or absence of erroneous operation based on result of detection by the state detection means and the operation specification information.
4. The wafer handling checker according to Claim 3, wherein the decision means has output means for generating sound when it decides the presence of erroneous operation.